

CyberOptics Semiconductor APPLICATION NOTE

Tokyo Electron Limited ACT Robot Teaching

SUMMARY

Teaching and monitoring TEL ACT wafer handling robot handoffs is now easy, accurate and efficient. ATS can be introduced into the tool from a cassette or FOUP without cooling the machine down, without removing any covers or heat shields and without connecting any cables. A special recipe is used to move the ATS to each plate pausing with the ATS resting on the raised transfer pins to view and measure the wafer offset with respect to the center of the plate. The recipe also moves the ATS into each spin cup with the chuck partially raised so the handoff offset can be verified or taught.



TEL ACT-8



ATS on pincette



TEL track target

BENEFITS

Saves 6 hours of tool time each time robot handoff positions need to be checked. Reduces service labor expense. Increases tool availability. Reduces contamination. Provides data to monitor the wafer transfer process. Accurate robot teaching minimizes particle adds and may enhance critical dimension process capability.

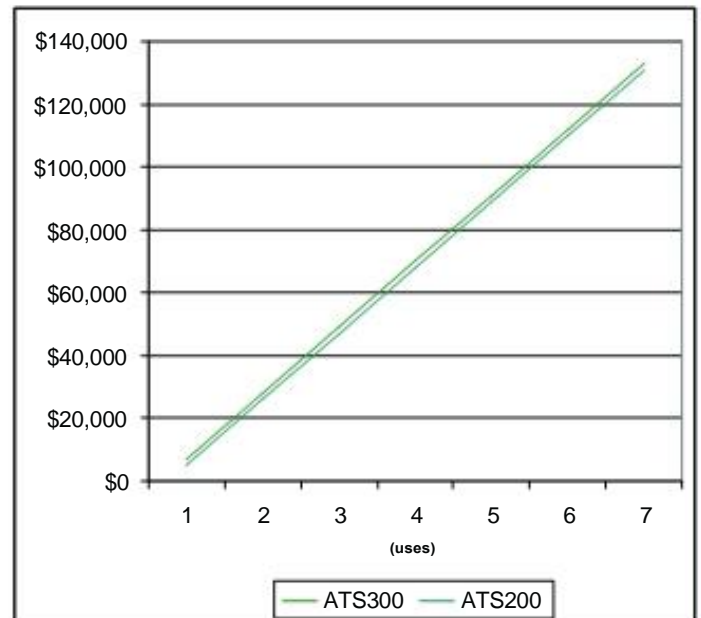
RETURN ON INVESTMENT

ROI in one use. Robot teach time reduced from 8 hours and 2 technicians to 2 hours and 1 technician. 400% MTTR reduction.

ORDERING INFORMATION

ATS200C for notched 200mm ACT-8s, ATS200CF for flatted 200mm ACT-8s, ATS300C for 300mm ACT-12s

ATS Return on Investment



CSsupport@cyberoptics.com

For information about CyberOptics' offices and global support network, please visit www.cyberoptics.com.